BiTS 2017

Making Contact - Contact Technology - 1 of 2



Burn-in & Test Strategies Workshop

www.bitsworkshop.org

March 5-8, 2017

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Session 6 Jason Mroczkowski

Session Chair

BiTS Workshop 2017 Schedule

Frontier Day

Tuesday March 7 - 1:30 pm

Making Contact

"High Current Final Test Contactor Development"

Thiha Shwe, Hisashi Ata – Texas Instruments

Kenichi Sato – Yokowo

"Customers Are the New Team Member for Board to Board Connectors"

Derek Biggs – Plastronics

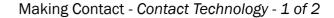
"WLCSP Contacting Technologies for 0.2 mm Pitch and Below"

Valts Treibergs - Xcerra Corporation

"Coming to terms with Burn-In sockets"

James Tong - Texas Instruments





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WLCSP Contacting Technologies for 0.2 mm Pitch and Below

Valts Treibergs Xcerra Corporation



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Agenda

- ATE Socket vs. Wafer Probe Head
- WLCSP at BiTS
- Spring Pins in WLCSP BiTS History
- WLCSP Technologies
 - Barrel & Plunger Spring Probes
 - Open Coil Spring Probes
 - MEMS Coil Spring Probes
 - Cantilever Technology
 - New Concept Monolithic MEMS Compliant Probe
- Space Transformers



WLCSP Contacting Technologies for 0.2 mm Pitch and Below

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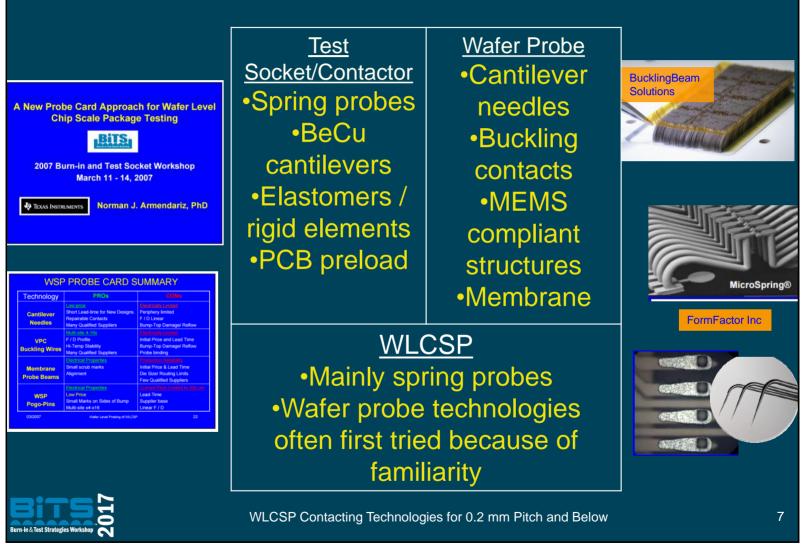
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ATE Contactor and Wafer Probe Head Quick Comparison

Test Socket/Contactor	<u>Wafer Probe</u>					
 High compliance 	 Planar wafer – minimal 					
•High power	compliance					
 Tri-temp testing 	 Controlled scrub 					
 0.3mm pitch and above 	 Very fine pitch – spread 					
 Reliable in very dirty 	out signals with space					
environments - handlers	transformers or by design					
Wafer Level Chip Scale Packaging (WLCSP)						
 More compliance needed vs. wafer probe because of 						
redistribution layer and larger bumps/flatness tolerances						
 Electrical performance requirements of ATE sockets 						
 Space transformers generally required except for low I/O 						
devices						
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Socket and Wafer Probe – Merging Technologies



Advances in WSP- Wafer Socket Pogo-Pin Probing

> Norman Armendariz James Tong 2010 Bits Workshop

TEXAS

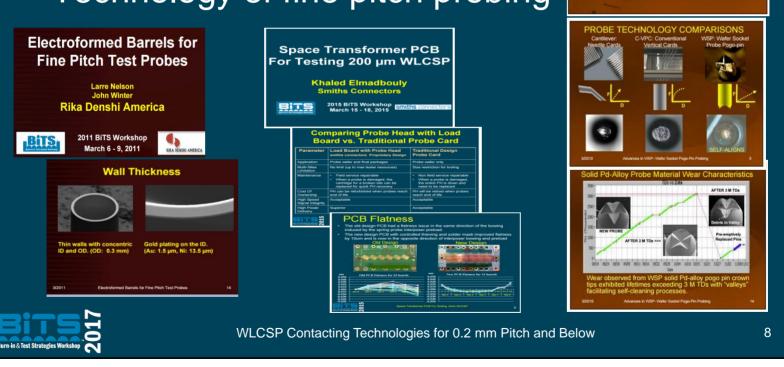
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WLCSP Basics – Well Covered at BiTS

- Probe components
- Space transformer concerns
- Technology of fine pitch probing



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Spring Probes in WLCSP

 Spring probe have proven performance in WLCSP real-world applications

Kelvin C Test Set Up #1: (Ball Contact) · Mount General	LEECO Industrial Inc.	Spring Probes and Probe Cards for Wafer-Level Test Jim Brandes Multitest	A Comparison of Probe Solutions for an RF WLCSP Product James Migliaccio RF Micro Devices 2013 BITS Workshop March 3 - 6, 2013 Witness Marks on Solder Balls	At Tri-temp for RF and non-RF products Tan Jin Sheng Intel Technology Asia Pte Ltd Edwin Valderama Intel Value Engineering/Technology Content Straworkehop 2016 BITS Workehop March 6 - 9, 2016
Improved Kevin Probes Into respective Gontact both probes onto probes onto Measure distance and capture images of ball marks Tost Results: • Probe marks • Mark distance		2013 BITS Workshop March 3 - 6 2013 Image: Constraint of the second march 3 - 6 2013 Mechanical Requirements Dictate Spring Probes Technology Proge* Probe Spring Probe Spring Probe/Membrane/Vertical 1/Vertical 2/ Type 1/Vertical 2/ 1/Vertical 3/Vertical 2/ Type Technology Proge* Probe Spring Probe/Membrane/Vertical 1/Vertical 2/ Type 1/Vertical 2/ 1/Vertical 3/Vertical 2/ Type Technology Proge* Probe Spring Probe/Membrane/Vertical 1/Vertical 2/ Type 1/Vertical 2/ 1/Vertical 3/Vertical 2/ Type Technology Proge* Probe Spring Probe/Spring 1/Vertical 2/ 1/Vertical 3/Vertical 2/ Type Technology Proge* Probe Spring 1/Vertical 2/ 1/Vertical 2/ Type Technology Proge* Probe Spring 1/Vertical 2/ 1/Vertical 2/ Type Technology Proge* Probe 1/Vertical 2/ Type Technology Proge* 1/Vertical 2/ Type Technology Con 1/Vertical 2/ Type	Contactors A & B Contactor C Spring Pin Pros/Cons	• Both types are usable, but which one is more suitable for the application?
		Min. Rots 0.5 mm 0.4 mm 0.3 mm 0.5 mm 0.7 mm Force*** 35 3.0g 15g 15g 25g 6g Tip Shage 10 a goints 2 points 1 point 1 point 1 point 4 paints Probe Mark off apex off apex off apex off apex off apex off apex * In Development ** Tip Crity ************************************	Pros: Pros will bottom out in the housing Probability of the onlard presenter possible Bottom on the onlard presenter possible Bottom on the onlard presenter possible Bottom on the onlard presenter of the onlard presenter of the onlard Probability of the onlard presenter of the onlard pr	Probe Needle vs Pogo Pin Proce Pogo Pin - Available for very fire pitch application - Generally cheaper - Baster probe-pad algriment to probe ip - Generally cheaper - Baster plananity control - Much easier to perform replacement in production - Baster plananity control - High contract force - Botter plananity control - High contract force - Botter probe force - High contract force - Owner maintenance - Probe-pad algrimment for probe force - Lower overdrive range - Owner in pitch (for now) - Lower overdrive range - Hadre to control plananity
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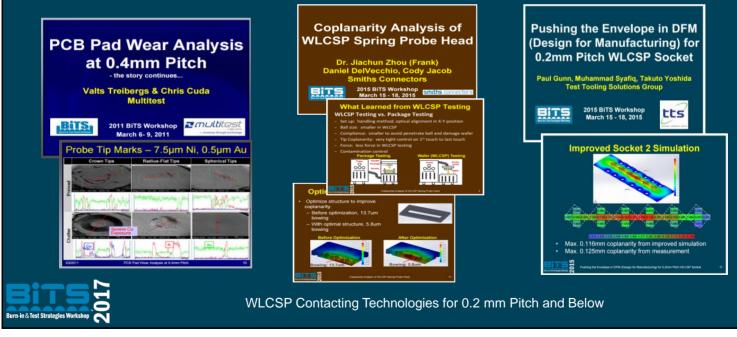
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Spring Probe Technology vs. Planarity

- Package test requires spring probe preload
- Preload causes socket bowing tip planarity across grid
- Analysis must be done to optimize



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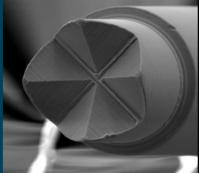
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WLCSP – Barrel/Plunger Spring Probes

- The most commonly available probe technologies available from a variety of suppliers
- 3 or 4 piece design
- Barrel can be machined, drawn or e-formed



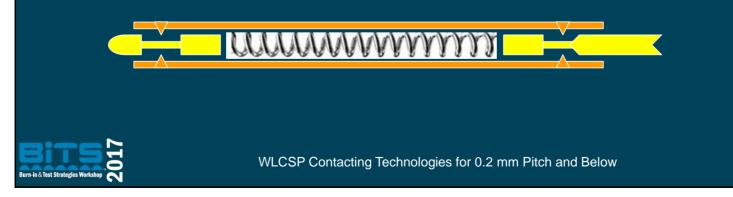
• Plungers plated or monolithic alloy



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WLCSP – Barrel/Plunger Spring Probes

- Since springs are contained within the barrel inner diameter (ID), their diameter is very small and must be very long
- Little to no controlled plunger/barrel biasing possible

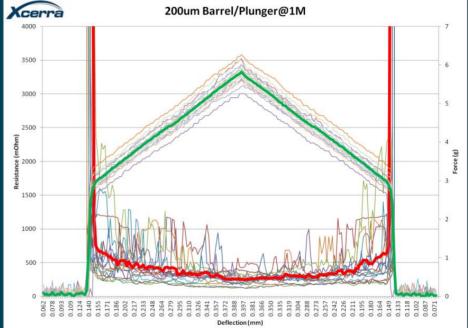


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Example Barrel/Plunger Spring Probe

- 5.7 g average force to 1M cycles
- $R_{contact} < 500 \text{ m}\Omega$
- 1.3 A Current Carrying Capacity (International SEMATECH Manufacturing Initiative)
- RF: >40 GHz @ -1dB





WLCSP Contacting Technologies for 0.2 mm Pitch and Below

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WLCSP – Open Coil Spring Probes

- Available from several suppliers
- 2 or 3 piece design spring could act as PCB side contact
- Coil spring acts as probe barrel
- Plungers plated or utilize monolithic alloy



WLCSP Contacting Technologies for 0.2 mm Pitch and Below

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WLCSP – Open Coil Spring Probes

- Springs are maximum diameter within the housing hole – best force and deflection possible
- Plungers permanently attached to springs

 may have protrusions into spring
- Springs often incorporate 'dead' coils
- Plunger rotation from spring compression – drilling effect

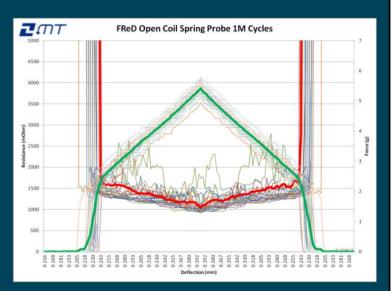
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Example – Open Coil Spring Probe

- Force 5 g through millions of touchdowns
- $R_{contact} > 1 \Omega$
- RF poor <1 GHz -1 dB (open coil design)
- RF good (closed and shorted coils – design optimized)

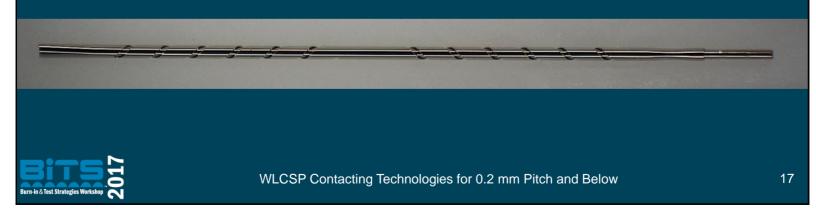




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WLCSP – MEMS Spring Probes

- Spring is manufactured from e-formed tubes and precision cut with controlled spiral structure
- Homogeneous alloy plunger
- Rotation or designed no-rotation possible
- Plunger permanently attached to spring

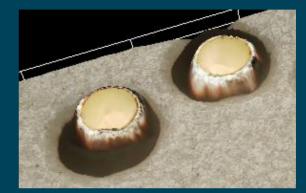


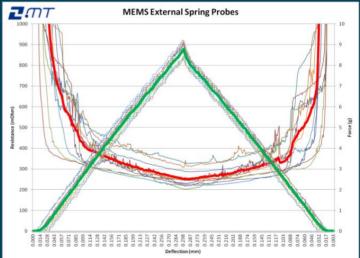
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WLCSP – MEMS Spring Probes

- Good probe normal force for probe size
- PCB interconnect side is metal tube – not ideal contact – very fragile
- $R_{contact} < 400 \text{ m}\Omega$
- RF: >30 GHz @ -1dB







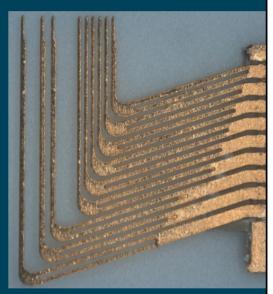
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WLCSP – Cantilever Technology

- Proven technology in wafer probe – redesigned to offer high compliance
- Single metal component PCB to DUT – no moving parts – 2 point contact
- PCB side compliance
 independent of DUT compliance
- Benefit of embedded space transformer/fan-out



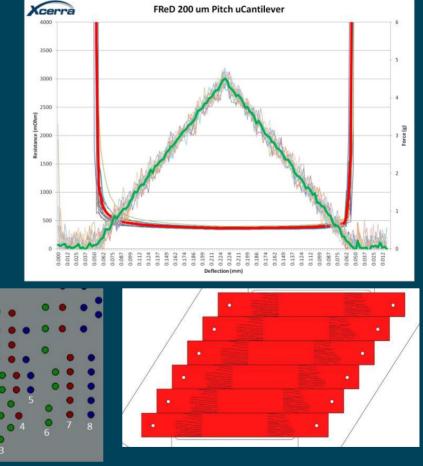


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WLCSP – Cantilever Technology

- Applicable to a limited number of applications – challenging on nonregular grids
- R_{contact} <400 mΩ little variance
- RF: not measured assumed poor unless impedance controlled



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Comparison of WLCSP Test Attributes

Contacting Technology	Ease of Application	DC Electrical	RF Electrical	COST		
Barrel/Plunger Spring Probe	Easy	Good	Good	\$\$		
Open Coil Spring Probe	Easy	ОК	Poor/Good	\$\$		
MEMS Spring Probe	Challenging	Good	Good	\$\$\$		
Cantilever	Challenging	Good	Poor	\$\$\$		
-	-	-		-		
Sweet Spot	Easy	Good	Good	\$		
WLCSP Contacting Technologies for 0.2 mm Pitch and Below 2						

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New Monolithic Vertical MEMS Probe

- Design high-compliance/low stress volumetric spring
- Built with MEMS manufacturing technology
- One metal component 2 point contact
- No elastomers or springs
- Optional gold plating all surfaces are external



WLCSP Contacting Technologies for 0.2 mm Pitch and Below

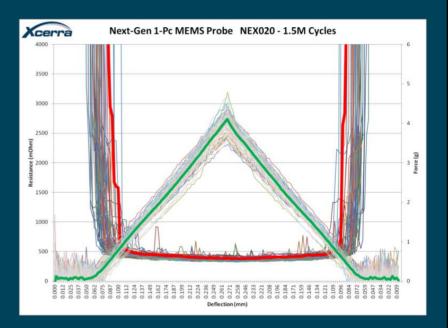
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Monolithic Vertical MEMS Probe - Nexus

- Lab test results through 1.5M touchdowns
 - Force: 4.5 g
 - $R_{contact} < 400 m\Omega$
 - ISMI current 400 mA
 - RF: 24.9 GHz (-1 dB-GSG .2 mm pitch)



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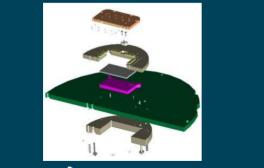
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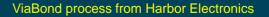
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PCB-Like Space Transformers

- Fine-pitch fan-out PCBs spread signals to the ATE interface board
- Multilayer Organic (MLO) / Multilayer Ceramic (MLC) boards available – product using package substrate technology becoming available in lower volumes
- Extreme care must be taken in design for signal and power integrity simulation and measurement essential
- Space transformers sit on intermediate board-board 'tower' or are direct bonded to ATE main board





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Non-PCB Space Transformer Option

- Directly connecting input to output via copper wires without planar stacked PCB structures and vias
- Full grid array with capability of 45 um pitch DUT side
- Impedance control possible for critical nets
- Shortest possible path



Direct Space Transformation technology from ThinkMEMS





WLCSP Contacting Technologies for 0.2 mm Pitch and Below

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Summary

- A variety of WLCSP contacting technologies are available today
- Depending on application, some solutions will work better than others
- Next-generation solutions allow for scaling 0.2 mm and below and are becoming more and more costeffective



WLCSP Contacting Technologies for 0.2 mm Pitch and Below

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